



1762/4

216-028A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : KATSIR, D. ET AL.
Serial No. : 09/745,347
Filed : December 21, 2000
For : METHOD FOR PRODUCING HIGH SURFACE
AREA FOIL ELECTRODES
Art Unit : 1762
Examiner : Brian Talbot

11/3/03
4.1/04
9/1/03

New York, NY 10036
January 23, 2003

Commissioner for Patents
Washington, D.C. 20231

AMENDMENT

This Amendment is being filed in response to the Office Action that was mailed July 23, 2002. Kindly amend the subject application as follows:

IN THE CLAIMS

Kindly amend claim 1 as follows:

1. (amended) A method for increasing the surface area of a substrate, comprising the steps of:
- (a) placing the substrate in an inert atmosphere, having a pressure of between 10^{-3} torr and 10^{-2} torr, into which oxygen has been introduced at a pressure of from one to two orders of magnitude less than said pressure of said inert atmosphere; and
 - (b) evaporating a valve metal onto the substrate under said oxygen-containing inert atmosphere, whereby the product has a fractal-like surface structure.

Kindly cancel claims 4 and 5.